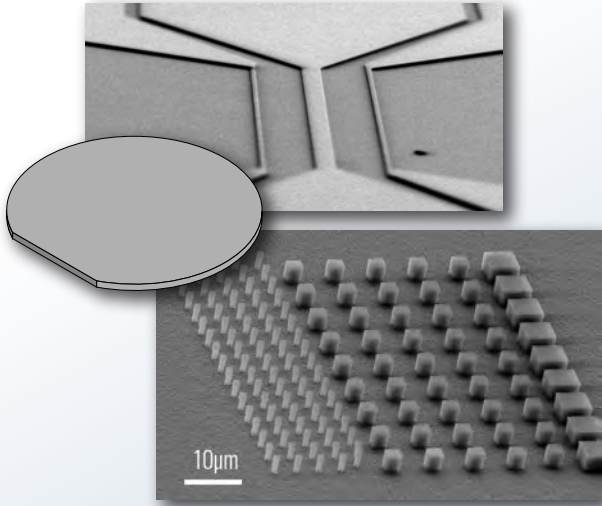


Photolithographie

Transfert de motifs sur plaquette de silicium

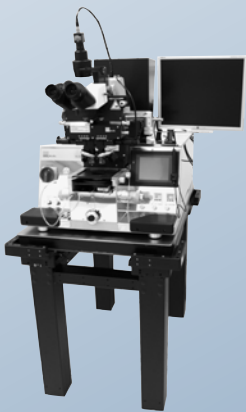


Résines

SU-8 2005
ShIPLEY 1805, 1818
AZ 2020
LOR



Equipements

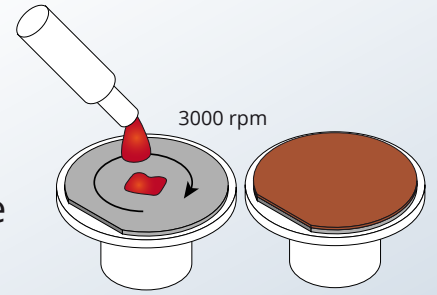


Karl Suss MJB4

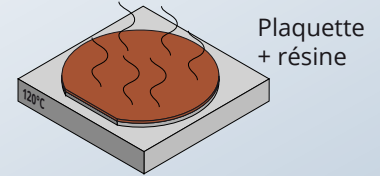


EVG 620

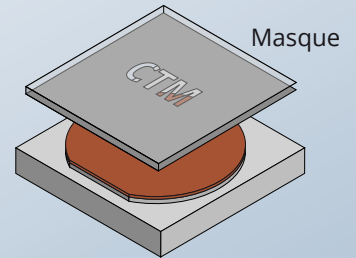
→ Enduction de résine à la tournette
Spincoating



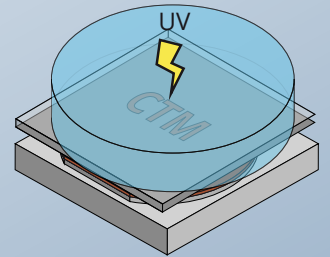
→ Recuit
Baking



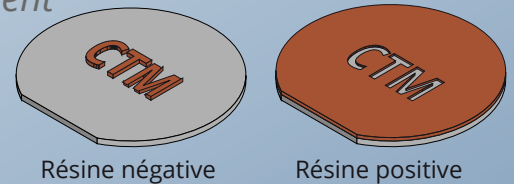
→ Alignement sous masque
Mask alignment



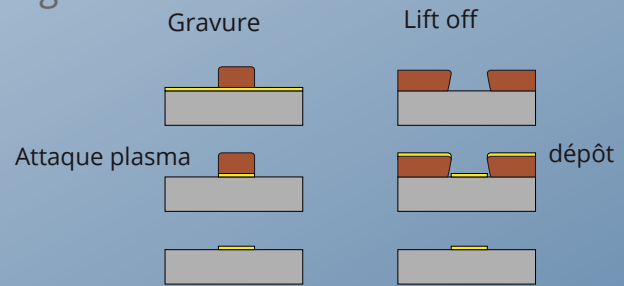
→ Exposition UV
UV exposure



→ Développement
Development



→ Gravure
Etching



Centrale de Technologie
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